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## U.S. PATENT DOCUMENTS

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## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

MDP	AR	IBM Technical Disclosure Bulletin, "Process for Selective Etching of Tantalum Oxide", IBM Corp., Vol. 27, No. 12 (May, 1985)					
		CHANG, Peng-Heng, et al., "Structures of Tantalum Pentoxide Thin Films Formed by Reactive Sputtering of Ta Metal", <u>Thin Film Solids</u> , Vol. 268, No. 1-2, pp. 56-63 (March 15, 1995)					
MDP	AS						
	AT						

EXAMINER <i>Marco S. Lijau-Loyola</i>	DATE CONSIDERED <i>10/13/2000</i>
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